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# **FACSIMILE COVER SHEET**

TO: \_EXAMINER S. GEBREMARIAM (U.S. PATENT AND TRADEMARK OFFICE)

CLIENT NUMBER: 54488

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FROM: CHRISTOPHER F. REGAN, REG. NO. 34,906

DATE: December 6, 2004

NUMBER OF PAGES (INCLUDING COVER SHEET): 12

#### **COMMENTS/INSTRUCTIONS:**

Re: U.S. Patent Application Serial No. 10/701,165 filed 11/4/03

Attached are the following documents:

Copy of PRELIMINARY AMENDMENT (pages 1-9 and replacement drawing)
Copy of return postcard acknowledging receipt in USPTO Mailroom on 11/4/03

The restriction requirement mailed on 12/2/04 incorrectly considers canceled Claims 1-11. We respectfully request that a new office action be issued directed to Claims 12-38 added by Preliminary Amendment of 11/4/04.

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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

DEC 0 6 2004

In re Patent Application of: MORIN ET AL.

Serial No. Not yet assigned

Filing Date: Herewith

For: SEMICONDUCTOR DEVICE WITH MOS )
TRANSISTORS WITH AN ETCH-STOP )
LAYER HAVING AN IMPROVED )
RESIDUAL STRESS LEVEL AND )
METHOD FOR FABRICATING SUCH A )
SEMICONDUCTOR DEVICE

I HEREBY CERTIFY THIS PAPER OR FEE IS BEING DEPOSITED WITH THE U.S. POSTAL SERVICE "EXPRESS MAIL POST OFFICE TO ADDRESSEE" SERVICE UNDER 37 CFR 1.10 ON THE DATE INDICATED BELOW AND IS ADDRESSED TO: MS PATENT APPLICATION, PO BOX 1450, ALEXANDRIA. VA 22313-1450.

EXPRESS MAIL NO: EV301516187US

DATE OF DEPOSIT: November 4, 2003

NAME: Justin (siece

### PRELIMINARY AMENDMENT

MS Patent Application Commissioner For Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Prior to the calculation of fees and examination of the present application, please enter the amendments and remarks set out below.

## In the Drawings:

Attached is one (1) replacement drawing sheet. The changes made to the drawings are explained in the remarks section below.

### In the Claims:

Claims 1-11 (Cancelled).

12. (New) A semiconductor device comprising: a semiconductor substrate;

at least one first MOS transistor and at least one second MOS transistor in said semiconductor substrate;

a dielectric layer on said at least one first MOS transistor and on said at least one second MOS transistor;

a first layer covering said at least one first MOS transistor and having a first residual stress level; and

a second layer covering said at least one first MOS transistor and said at least one second MOS transistor and having a second residual stress level different than the first residual stress level.

- 13. (New) A semiconductor device according to Claim 12, wherein said first and second layers have different thicknesses.
- 14. (New) A semiconductor device according to Claim 12, wherein said dielectric layer includes contact openings therethrough for providing electrical connection to said at least one first MOS transistor and to said at least one second MOS transistor.
- 15. (New) A semiconductor device according to Claim 12, wherein said at least one first MOS transistor comprises NMOS transistors and said at least one second MOS transistor comprises PMOS transistors, and wherein said first and second layers have opposite residual stress levels.

- 16. (New) A semiconductor device according to Claim 15, wherein said first layer has a positive residual stress level above said NMOS transistors, and said second layer has a negative residual stress level above said PMOS transistors.
- 17. (New) A semiconductor device according to Claim 12, wherein said at least one first MOS transistor comprises PMOS transistors and said at least one second MOS transistor comprises NMOS transistors, and wherein said first and second layers have opposite residual stress levels.
- 18. (New) A semiconductor device according to Claim 17, wherein said first layer has a negative residual stress level above said PMOS transistors, and said second layer has a positive residual stress level above said NMOS transistors.
- 19. (New) A semiconductor device according to Claim 12, wherein a zone formed by said second layer overlapping said first layer has a substantially zero residual stress level.
  - 20. (New) A semiconductor device comprising; a semiconductor substrate;
- at least one NMOS transistor and at least one PMOS transistor in said semiconductor substrate;
- a dielectric layer on said at least one NMOS transistor and on said at least one PMOS transistor;
- a first layer covering said at least one NMOS transistor and having a first residual stress level; and
  - a second layer covering said at least one NMOS

transistor and said at least one PMOS transistor and having a second residual stress level different than the first residual stress level.

- 21. (New) A semiconductor device according to Claim 20, wherein said first and second layers having different thicknesses.
- 22. (New) A semiconductor device according to Claim 20, wherein said dielectric layer includes contact openings therethrough for providing electrical connection to said at least one NMOS transistor and to said at least one PMOS transistor.
- 23. (New) A semiconductor device according to Claim 20, wherein said first and second layers have opposite residual stress levels.
- 24. (New) A semiconductor device according to Claim 23, wherein said first layer has a positive residual stress level above said at least one NMOS transistor, and said second layer has a negative residual stress level above said at least one PMOS transistor.
- 25. (New) A semiconductor device according to Claim 20, wherein a zone formed by said second layer overlapping said first layer has a substantially zero residual stress level.
  - 26. (New) A semiconductor device comprising: a semiconductor substrate;

at least one PMOS transistor and at least one NMOS transistor in said semiconductor substrate;

- a dielectric layer on said at least one PMOS transistor and on said at least one NMOS transistors;
- a first layer covering said at least one PMOS transistor and having a first residual stress level; and
- a second layer covering said at least one PMOS transistor and said at least one NMOS transistor and having a second residual stress level different than the first residual stress level.
- 27. (New) A semiconductor device according to Claim 26, wherein said first and second layers have different thicknesses.
- 28. (New) A semiconductor device according to Claim 26, wherein said dielectric layer includes contact openings therethrough for providing electrical connection to said at least one PMOS transistor and to said at least one NMOS transistor.
- 29. (New) A semiconductor device according to Claim 26, wherein said first and second layers have opposite residual stress levels.
- 30. (New) A semiconductor device according to Claim 29, wherein said first layer has a negative residual stress level above said at least one PMOS transistor, and said second layer has a positive residual stress level above said at least one NMOS transistor.

32. (New) A method for fabricating a semiconductor device comprising:

forming at least one first MOS transistor and at least one second MOS transistor in a semiconductor substrate;

forming a dielectric layer on the at least one first MOS transistor and on the at least one second MOS transistor;

forming a first layer covering the at least one first MOS transistor and having a first residual stress level; and

forming a second layer covering the at least one first MOS transistor and the at least one second MOS transistor and having a second residual stress level different than the first residual stress level.

- 33. (New) A method according to Claim 32, wherein the first and second layers have different thicknesses.
- 34. (New) A method according to Claim 32, further comprising forming contact openings through the dielectric layer for providing electrical connection to the at least one first MOS transistor and to the at least one second MOS transistor.
- 35. (New) A method according to Claim 32, wherein forming the first layer comprises:

forming the first layer covering the at least one

<sup>31. (</sup>New) A semiconductor device according to Claim 26, wherein a zone formed by said second layer overlapping said first layer has a substantially zero residual stress level.

first MOS transistor and the at least one second MOS transistor;

forming a mask on the at least one first MOS transistor;

removing the first layer on the at least one second MOS transistor; and

removing the mask.

- 36. (New) A method according to Claim 32, further comprising performing a localized treatment of the first and second layers that overlap the at least one first MOS transistor for modifying the second residual stress level of the second layer.
- 37. (New) A method according to Claim 36, wherein performing the localized treatment comprises implanting ions into the second layer.
- 38. (New) A method according to Claim 37, wherein germanium ions are implanted into the second layer.

#### REMARKS

Attached hereto is one (1) sheet of replacement drawings in which FIGS. 1-2 are being labeled as prior art.

It is believed that all of the claims are patentable over the prior art. For better readability and the Examiner's convenience, the newly submitted claims differ from the translated counterpart claims which are being canceled. The newly submitted claims do not represent changes or amendments that narrow the claim scope for any reason related to the statutory requirements for patentability. Accordingly, after the Examiner completes a thorough examination and finds the claims patentable, a Notice of Allowance is respectfully requested in due course. Should the Examiner determine any minor informalities that need to be addressed, he is encouraged to contact the undersigned attorney at the telephone number below.

Respectfully submitted,

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